

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In Re Patent Application:	:	Group Art Unit: 1744
<b>Ming-Chun Chou</b>	:	
	:	
Serial Number: 10/823,955	:	Examiner: <b>Karls, Shay Lynn</b>
	:	
Filed: <b>April 14, 2004</b>	:	Confirmation No.: 5433
	:	
Title: <b>Brush Positioning Device For A Wafer Cleaning Station</b>	:	Attorney Docket No.: N1161-00026
	:	

Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT AND RESPONSE AFTER FINAL**

Sir:

This paper is responsive to the final Office Action dated February 12, 2008 in the above-captioned application. A request for continued examination (RCE) is submitted herewith. Kindly enter the following:

**Amendments to the claims** are reflected in the claim listing which begins on page 2 of this paper.

**Remarks** begin on page 6 of this paper.